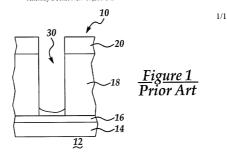
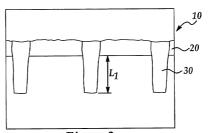
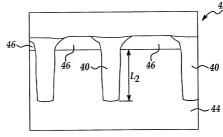
For: METHOD FOR FORMING VIA AND CONTACT HOLES WITH DEEP UV PHOTORESIST Attorney Docket No.: 67,200-549





<u>Figure 2</u> Prior Art



<u>Figure 3</u>